

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

PECEIVED Examiner. L.
TC 12003 P.T.O. Confirmation No.: 5542
TON PROCESS AND DRY DRY ETCHING METHOD, MICROFABRICATION PROCESS AND DRY

ETCHING MASK

Serial No.: 09/816,784

Filed: March 26, 2001

AMENDMENT UNDER 37 CFR §1.111

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

In re the Application of: HATTORI, Kazuhiro

August 8, 2003

Sir:

For:

In response to the Office Action dated April 8, 2003, extended to August 8, 2003 by a one (1) month Petition for Extension of Time, please amend the above-identified application as follows: